MPG HLL Status





- ▶ MPG HLL is working on the installation of a process line for
 - → Post processing of up to 200 mm CMOS wafers
 - → Fabrication of actively cooled interposers with micro-channels and TSVs

 - → Hybrid bonding of post-processed CMOS wafers or single CMOS chips to sensors wafers

Current status

- → The clean room of MPG HLL was relocated to a new and larger building
- → Tests with equipment manufacturer finished, tool configuration done, purchasing in progress
- → Relocated equipment currently in the hook-up phase, qualification to follow









Planned technology extension





Towards post-processing, micro-machining, vertical integration, and advanced heat management

- Deep reactive Ion etching for TSVs, micro-channels
 - → **Ordered**, to be installed summer 2024
- Chemical mechanical polishing (prep for planarization and wafer bonding)
 - → **Ordered**, to be installed autumn 2024
- > Low temperature direct wafer bonding line
 - → Plasma activation, cleaning, bonding, metrology
 - → Process defined, pre-tests accomplished, tendering in progress
- Hybrid bonding tool
 - → W2W, C2W aligned bonding (bumpless fine pitch interconnect)
 - → Process defined, tendering in progress
 - → Lead time about 12 months





A few few pictures from past projects – more to come!



































